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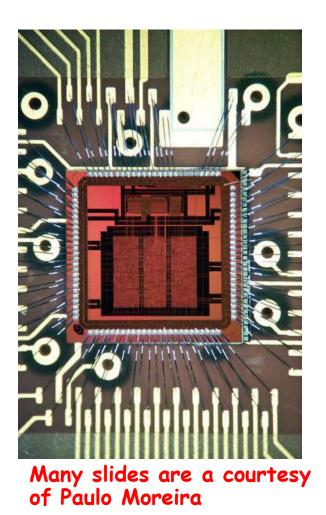
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Introduction to VLSI Digital Design Scaling

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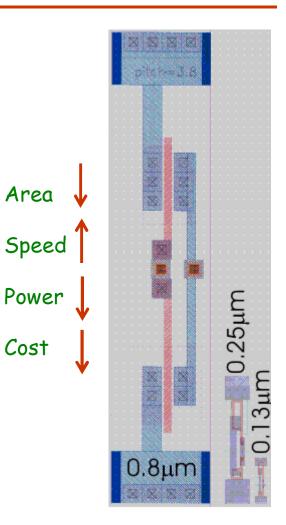
# Outline

- Introduction
- Transistors
- The CMOS inverter
- Technology
- Scaling
  - Scaling objectives
  - Scaling variables
  - Scaling consequences
- Gates
- Sequential circuits
- Storage elements



# Technology scaling

- Technology scaling has a <u>threefold</u> <u>objective</u>:
  - Increase the transistor density
  - Reduce the gate delay
  - Reduce the power consumption
- At present, between two technology generations, the objectives are:
  - Doubling of the transistor density;
  - Reduction of the gate delay by 30% (43% increase in frequency);
  - Reduction of the power by 50% (at 43% increase in frequency);



## Technology scaling

- How is scaling achieved?
  - All the device dimensions (lateral and vertical) are reduced by  $1/\alpha$
  - Concentration densities are increased by  $\alpha$  to make the junctions depletion region smaller by  $1/\alpha$
  - Device voltages reduced by  $1/\alpha$  (for constant field)
  - Typically  $1/\alpha = 0.7$  (30% reduction in the dimensions)

# Technology scaling

#### • The scaling variables are:

<ul> <li>Supply voltage:</li> </ul>	$V_{dd}$	$\rightarrow$	V <sub>dd</sub> / $\alpha$
<ul> <li>Gate length:</li> </ul>	L	$\rightarrow$	L/α
<ul> <li>Gate width:</li> </ul>	W	$\rightarrow$	<b>W /</b> α
<ul> <li>Gate-oxide thickness:</li> </ul>	† <sub>ox</sub>	$\rightarrow$	$t_{ox}$ / $\alpha$
<ul> <li>Junction depth:</li> </ul>	Xj	$\rightarrow$	<b>Χ</b> j / α
<ul> <li>Substrate doping:</li> </ul>	Ň <sub>A</sub>	$\rightarrow$	$N_A \times \alpha$

This is called <u>constant field</u> scaling because the electric field across the gate-oxide does not change when the technology is scaled

If the power supply voltage is maintained constant the scaling is called <u>constant voltage</u>. In this case, the electric field across the gate-oxide increases as the technology is scaled down.

Due to gate-oxide breakdown, below  $0.8\mu m$  only "constant field" scaling is used.

#### Scaling consequences

Some consequences of 30% scaling in the constant field regime ( $\alpha = 1.43$ ,  $1/\alpha = 0.7$ ):

• Device/die area:

 $W \times L \rightarrow (1/\alpha)^2 = 0.49$ 

- "Historically", microprocessor <u>die size grows</u> about 25% per technology generation! This is a result of added functionality.
- Transistor density:

(unit area) /(W  $\times$  L)  $\rightarrow$   $\alpha^2$  = 2.04

- In practice, <u>memory density</u> has been scaling as expected.

### Scaling consequences

• Gate capacitance:

W × L / 
$$t_{ox} \rightarrow 1/\alpha = 0.7$$

• Drain current:

(W/L) 
$$\times$$
 (V²/t<sub>ox</sub>)  $\rightarrow$  1/ $\alpha$  = 0.7

• Gate delay:

 $(C \times V) / I \rightarrow 1/\alpha = 0.7$ Frequency  $\rightarrow \alpha = 1.43$ 

 In practice, microprocessor frequency has doubled every technology generation (2 to 3 years)! This faster increase rate is due to super-pipelined architectures ("less gates per clock cycle")

### Scaling consequences

• Power:

$$C \times V^2 \times f \rightarrow (1/\alpha)^2 = 0.49$$

• Power density:

$$1/t_{ox} \times V^2 \times f \rightarrow 1$$

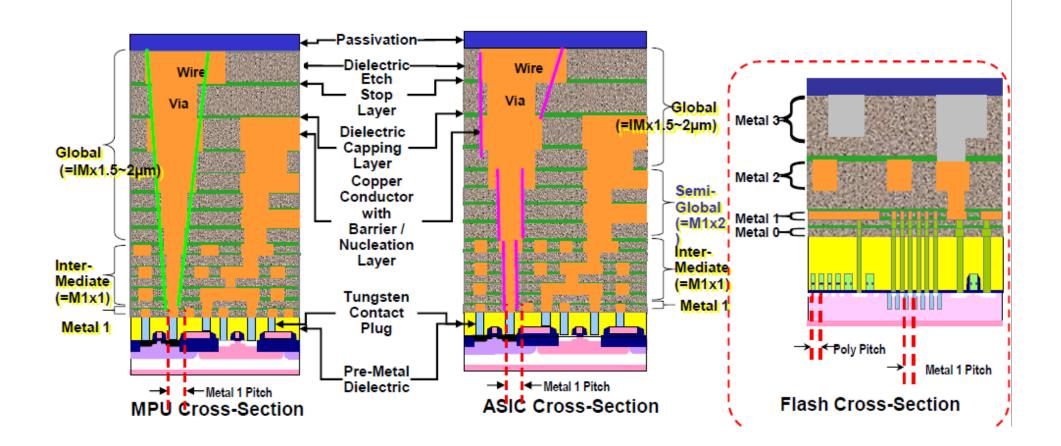
- In practice, the power density has been increasing faster than foreseen by the simple scaling theory. This is due to the faster than foreseen increase in frequency

## Interconnects scaling

- Interconnects scaling:
  - Higher densities are only possible if the interconnects also scale.
  - Reduced width  $\rightarrow$  increased resistance
  - Denser interconnects  $\rightarrow$  <u>higher capacitance</u>
  - To account for <u>increased parasitics</u> and <u>integration</u> <u>complexity</u> more interconnection layers are added:
    - thinner and tighter layers  $\rightarrow$  local interconnections
    - thicker and sparser layers  $\rightarrow$  global interconnections and power

#### IC Cross Sections

Source: ITRS

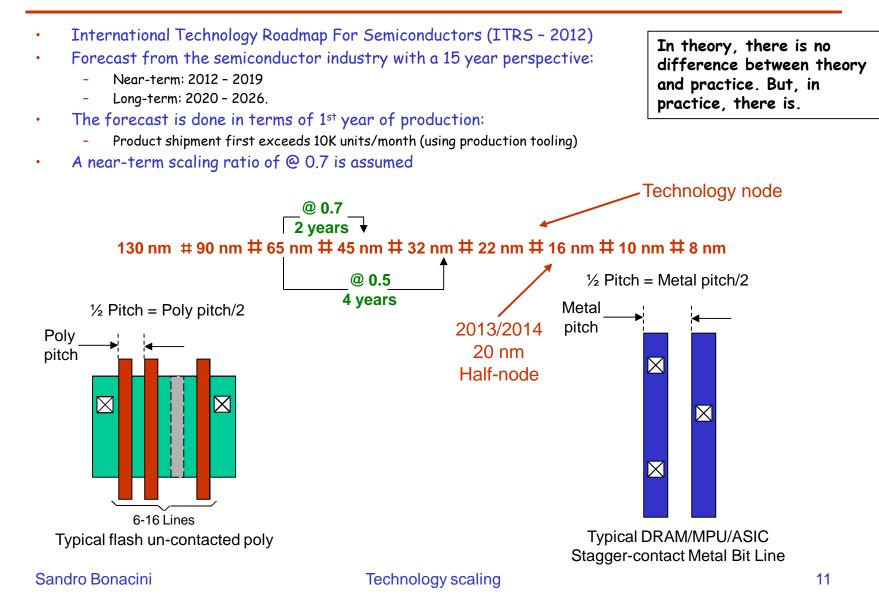


Technology scaling

# Scaling table

Supply voltage (Vdd) $1/\alpha$ $1/\alpha$ $1$ Length (L) $1/\alpha$ $1/\alpha$ $1/\alpha$ Width (W) $1/\alpha$ $1/\alpha$ $1/\alpha$ Gate-oxide thickness (tox) $1/\alpha$ $1/\alpha$ $1/\alpha$ Junction depth (Xj) $1/\alpha$ $1/\alpha$ $1/\alpha$ Substrate doping (NA) $\alpha$ $\alpha$ $\alpha$ Electric field across gate oxide (E) $1$ $\alpha$ Depletion layer thickness $1/\alpha$ $1/\alpha$ Gate area (Die area) $1/\alpha^2$ $1/\alpha^2$ DeviceGate capacitance (load) (C) $1/\alpha$ $1/\alpha$ Drain-current (Idss) $1/\alpha$ $\alpha$ Transconductance (gm) $1/\alpha$ $\alpha^3$ Gate delay $1/\alpha^2$ $\alpha$ Gate delay $1/\alpha$ $1/\alpha^2$ Power density $1$ $\alpha^3$ Power-Delay product $1/\alpha^3$ $1/\alpha$ Sandro BonaciniTechnology scaling	Parameter	Constant Field	Cons	tant Voltage
Width (W) $1/\alpha$ $1/\alpha$ $1/\alpha$ $1/\alpha$ Gate-oxide thickness ( $t_{ox}$ ) $1/\alpha$ $1/\alpha$ $1/\alpha$ Junction depth ( $X_j$ ) $1/\alpha$ $1/\alpha$ $1/\alpha$ Substrate doping ( $N_A$ ) $\alpha$ $\alpha$ $\alpha$ Electric field across gate oxide (E)1 $\alpha$ Depletion layer thickness $1/\alpha$ $1/\alpha$ Gate area (Die area) $1/\alpha^2$ $1/\alpha^2$ Gate capacitance (load) (C) $1/\alpha$ $1/\alpha$ Drain-current ( $I_{dss}$ ) $1/\alpha$ $\alpha$ Transconductance ( $g_m$ ) $1/\alpha$ $\alpha$ Gate delay $1/\alpha$ $\alpha$ Current density $\alpha$ $\alpha^3$ Power density1 $\alpha^3$ Power-Delay product $1/\alpha^3$ $1/\alpha$	Supply voltage (V <sub>dd</sub> )	1/α	1	↑ <sup>−</sup>
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Electric field across gate oxide (E)1 $\alpha$ Depletion layer thickness $1/\alpha$ $1/\alpha$ Gate area (Die area) $1/\alpha^2$ $1/\alpha^2$ Gate capacitance (load) (C) $1/\alpha$ $1/\alpha$ Drain-current ( $I_{dss}$ ) $1/\alpha$ $\alpha$ Transconductance ( $g_m$ ) $1/\alpha$ $\alpha$ Gate delay $1/\alpha$ $1/\alpha^2$ Current density $\alpha$ $\alpha^3$ Dower density $1/\alpha^3$ $1/\alpha$	Junction depth (Xi)	1/α	1/α	
Depletion layer thickness $1/\alpha$ $1/\alpha$ Gate area (Die area) $1/\alpha^2$ $1/\alpha^2$ $1/\alpha^2$ Gate capacitance (load) (C) $1/\alpha$ $1/\alpha$ $1/\alpha$ Drain-current ( $I_{dss}$ ) $1/\alpha$ $\alpha$ Transconductance ( $g_m$ ) $1/\alpha$ $\alpha$ Gate delay $1/\alpha$ $1/\alpha^2$ Current density $\alpha$ $\alpha^3$ DC & Dynamic power dissipation $1/\alpha^2$ $\alpha$ Power density $1$ $\alpha^3$ Power-Delay product $1/\alpha^3$ $1/\alpha$	Substrate doping (N <sub>A</sub> )	α	α	
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Gate capacitance (load) (C) $1/\alpha$ $1/\alpha$ RepercussionDrain-current ( $I_{dss}$ ) $1/\alpha$ $\alpha$ Transconductance ( $g_m$ ) $1/\alpha$ $\alpha$ Gate delay $1/\alpha$ $1/\alpha^2$ Current density $\alpha$ $\alpha^3$ DC & Dynamic power dissipation $1/\alpha^2$ $\alpha$ Power density $1$ $\alpha^3$ Power-Delay product $1/\alpha^3$ $1/\alpha$	Depletion layer thickness	1/α	1/α	
Gate capacitance (load) (C) $1/\alpha$ $1/\alpha$ RepercussionDrain-current ( $I_{dss}$ ) $1/\alpha$ $\alpha$ $\alpha$ Transconductance ( $g_m$ )1 $\alpha$ $1/\alpha^2$ Gate delay $1/\alpha$ $1/\alpha^2$ $\alpha$ Current density $\alpha$ $\alpha^3$ $\alpha$ DC & Dynamic power dissipation $1/\alpha^2$ $\alpha$ Power density1 $\alpha^3$ $1/\alpha$ Power-Delay product $1/\alpha^3$ $1/\alpha$	Gate area (Die area)	<b>1/</b> α <sup>2</sup>	<b>1/</b> α²	Device
Drain-current $(I_{dss})$ $1/\alpha$ $\alpha$ Transconductance $(g_m)$ 1 $\alpha$ Gate delay $1/\alpha$ $1/\alpha^2$ Current density $\alpha$ $\alpha^3$ DC & Dynamic power dissipation $1/\alpha^2$ $\alpha$ Power density1 $\alpha^3$ Power-Delay product $1/\alpha^3$ $1/\alpha$	Gate capacitance (load) (C)	1/α	1/α	
Gate delay $1/\alpha$ $1/\alpha^2$ Current density $\alpha$ $\alpha^3$ DC & Dynamic power dissipation $1/\alpha^2$ $\alpha$ Power density1 $\alpha^3$ Power-Delay product $1/\alpha^3$ $1/\alpha$	Drain-current (I <sub>dss</sub> )	1/α	α	
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DC & Dynamic power dissipation $1/\alpha^2$ $\alpha$ RepercussionPower density1 $\alpha^3$ $1/\alpha^3$ I/ $\alpha$ Power-Delay product $1/\alpha^3$ $1/\alpha$ I/ $\alpha$	Current density	α	$\alpha^3$	
Power density1 $\alpha^3$ Power-Delay product $1/\alpha^3$ $1/\alpha$	DC & Dynamic power dissipation	$1/\alpha^2$	α	
	Power density	1	$\alpha^3$	Repercussion
Sandro Bonacini Technology scaling	Power-Delay product	<b>1/</b> α <sup>3</sup>	1/α	Ļ
	Sandro Bonacini	Technology scaling		1

## 2013 and beyond ...



## 2013 and beyond ...

ITRS Road Map, 2012 edition:	2013	2017	2020	2023 (year of first production)
Gate length, physical (nm)	20	14	11	8 (7 years for $\frac{1}{2}$ L, 2 nodes)
Gate length, printed (nm)	28	17.7	12.5	8.8
Flash Poly ½ pitch (nm)	18	13	10	8 (flash drives the scaling)
DRAM $\frac{1}{2}$ pitch (nm)	28	179	12.6	8.9
Wafer diameter (mm)	300	450	450	450 (wafers getting larger)
Wiring levels (maximum)	13	14	14	15 (tall metal stack)
DRAM:				
Bits/chip (Gbits)	4.29	8.59	34.36	34.36 (increase and saturate)
Chip size (mm <sup>2</sup> )	35	19	37	19 (small chips for low-cost bits)
Gbits/cm <sup>2</sup>	12.24	46.25	92.5	185
Flash:				
Bits/chip (Gbits) SLC	69	137	275	412 (3D flash starts in 2016)
Chip size (mm <sup>2</sup> )	149.8	135.88	162.42	158.13
Gbits/cm <sup>2</sup>	45.9	101	169	261
Bits/chip (Gbits) MLC [3D 2 bits/o	cell] -	550	1100	2199 (end of hard disks??)
Chip size (mm <sup>2</sup> )	-	159.82	102.73	124.03
Gbits/cm <sup>2</sup>	-	344	1070	1770
μP (high performance):				
Transistors/chip (Millions)	8848	17696	35391	70782 (doubling cores)
Chip size (mm <sup>2</sup> )	260	206	206	206 (small chips for cheap MIPS)
Transistors/cm <sup>2</sup> (M/cm <sup>2</sup> )	3403	8575	17150	34300
Total pads	3072	3072	3072	3072 (66.7% for power/ground)
Performance:				
On-Chip clock (GHz)	4	4.74	5.33	6 (saturate)
GFLOPs [Not ITRS data!] ~ Power supply:	100 (*)	237	533	1200 [not ITRS data!]
Vdd (V):	0.85	0.75	0.68	0.62 (low-power for freg. increase)
Maximum allowable power (W)	149	130	130	? (With heat sink)